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PATENT  
8017-1094

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Toshiji TAIJI et al. Conf. 2404

Application No. 10/616,914 Group 1765

Filed July 11, 2003 Examiner L. Umez Eronini

SLURRY FOR CHEMICAL MECHANICAL POLISHING

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents August 31, 2005  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In compliance with Rules 1.97 and 1.98, and in fulfillment of the duty of disclosure under Rule 1.56, the cited documents are made of record on the enclosed PTO Form-1449.

A concise explanation of the relevance of these items is that these references were cited in an Office Action dated May 31, 2005 in the corresponding Korean Application. A copy of the Official Action in which they were cited is attached hereto, with what is believed to be the pertinent portion enclosed in a wavy line. **An English translation of the Japanese enclosed portion is also attached hereto.**

Under the provisions of 37 CFR 1.97(e), the undersigned hereby certifies that each item of information contained in this Information Disclosure Statement was first

Docket No. 8017-1094  
Appln. No. 10/616,914

cited in any communication from a foreign Patent Office in a counterpart foreign application not more than three months prior to the filing of this Statement.

Respectfully submitted,

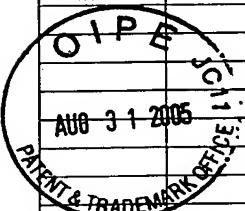
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RJP/mjr  
August 31, 2005

<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>  (Use several sheets if necessary)		Attorney Docket No.: <b>8017-1094</b>		Application No.: <b>10/616,914</b>	
		Applicant: <b>Toshiji TAIJI et al.</b>			
		Filing Date: <b>July 11, 2003</b>		Group Art Unit: <b>1765</b>	
<b>U.S. PATENT DOCUMENTS</b>					
Examiner Initial	Document Number	Date	Name	Class	Subclass
Filing date (if appropriate)					
					
<b>FOREIGN PATENT DOCUMENTS</b>					
Examiner Initial	Document Number	Date	Country	Class	Subclass
Translation Yes      No					
	KR2001-20384	03/2001	Korea		
	WO 98/49723	11/1998	International		
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>					
EXAMINER:		DATE CONSIDERED			
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.					

\* Abstract provided for the Examiner's convenience

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